

# Reliable High-Performance Gate Oxides for wide Band Gap Devices

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## Motivation

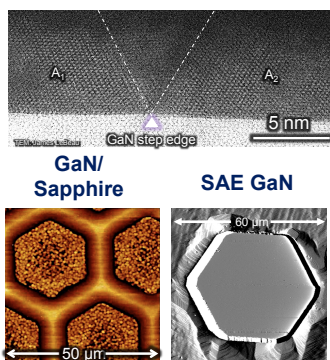
- Wide band gap semiconductor devices can improve the performance of energy conversion systems.
- Voltage control, normally-off devices based on GaN have seen limited deployment
- Lack of deployment stems from issues related to switching stability/repeatability/reliability and conduction.
- All of these issues are related to defects in the insulating component of the device (gate oxide/passivation layer)

## FY15 Activities

- Identify means to reduce threading defect density in GaN
- Quantify band offsets at MgO/GaN interface
- Quantify interface trap density at MgO/GaN and CaO/GaN interfaces

## Eliminating GaN Interface Defects

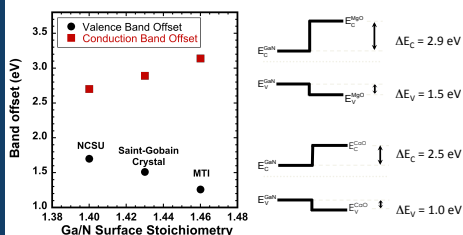
- GaN surface steps lead to defects in insulating layer – potential source of breakdown and traps
- Selected area epitaxy (SAE) of GaN and controlling growth via supersaturation allows for growth of atomically flat material over large areas



SAE eliminates step edges

## Band Structure: MgO/GaN

- Band structure measured using X-ray photoelectron spectroscopy in molecular-beam grown MgO/GaN
- Several sources of GaN were investigated to identify design principles needed for different GaN device manufacturers

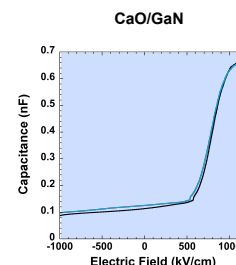
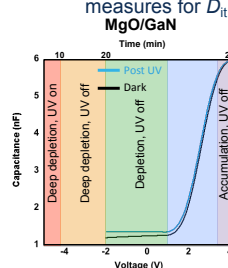


- Band offsets > 1 eV
  - Suitable for both n- and p-type devices

Dielectric   GaN	VBO (eV)	CBO (eV)	CBO
La <sub>2</sub> O <sub>3</sub>	0.63	1.5	SNL
Gd <sub>2</sub> O <sub>3</sub>	0.41	1.6	SNL
MgO	1.5	2.9	SNL
CaO	1.0	2.5	NCSU
Ga <sub>2</sub> O <sub>3</sub>	1.4	0.1	[1]
SiO <sub>2</sub>	2.4	3.0	[2]
Al <sub>2</sub> O <sub>3</sub>	1.8	1.3	[3]
HfO <sub>2</sub>	0.5	1.5	[2]

## Electronic Properties: CaO & MgO/GaN

- MgO/CaO (30 nm)/GaN ( $N_d = 2 \times 10^{18} \text{ cm}^{-3}$ ) devices prepared and C-V and I-V characteristics measured
- UV-assisted C-V technique utilized
  - Provides one of the most conservative and complete measures for  $D_{it}$



Average  $D_{it}$  across band gap:

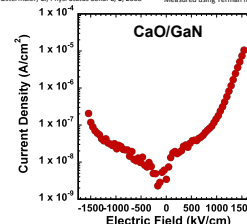
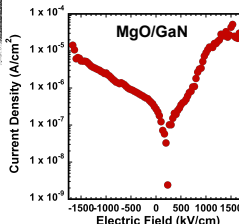
$$D_{it} = \frac{C_{ox}}{qA} \left( \frac{\Delta V}{E_g} \right)$$

MgO  $D_{it}$ :  $4 \times 10^{11} \text{ eV}^{-1} \text{ cm}^{-2}$

CaO  $D_{it}$ :  $3 \times 10^{11} \text{ eV}^{-1} \text{ cm}^{-2}$

Dielectric   GaN	$D_{it} (\text{eV}^{-1} \text{ cm}^{-2})$	Reference
La <sub>2</sub> O <sub>3</sub>	$8 \times 10^{11}$	SNL
MgO	$4 \times 10^{11}$	SNL
CaO	$3 \times 10^{11}$	SNL
Ga <sub>2</sub> O <sub>3</sub>	$4.2 \times 10^{11}$	[4]
Si <sub>3</sub> N <sub>4</sub>	$5 \times 10^{12}$	[5]
Al <sub>2</sub> O <sub>3</sub>	$3 \times 10^{12}$	[6]
Al <sub>2</sub> O <sub>3</sub>	$5 \times 10^{11}$	[7]
SiO <sub>2</sub>	$2 \times 10^{11}$	[8]

<sup>1</sup>Chen, Y., Semicond. Sci. Technol., 25, 2010.  
<sup>2</sup>Mishra, U., J. Appl. Phys., 106, 2009.  
<sup>3</sup>Ostermeier, C., Phys. Status Solidi C, 5, 2008.  
<sup>4</sup>Wu, Y., Appl. Phys. Lett., 90, 2007.  
<sup>5</sup>Ravindra, T., Appl. Surf. Sci., 189-190, 2000.  
<sup>6</sup>Measured using Terman method



- $D_{it}$  values are among the lowest reported for a gate insulator on GaN
- Positive threshold voltages observed
  - Implications for safe (enhancement mode, normally off) operation
- Low leakage current in both depletion and accumulation
  - High performance operation with efficient switching

## FY15 Publications and Impact

- E.A. Paisley, M. Brumbach, A. Allerman, A. Armstrong, R. Kaplar, A. Baca, S. Atcitty, and J.F. Ihlefeld, "Spectroscopic investigations of band offsets of MgO/AlGaIn heterostructures with varying AlN content," Applied Physics Letters, *Accepted*
- Developing a new understanding of semiconductor surface chemistry and impact on device properties (band offsets)
- Developed growth techniques for smooth GaN with low surface and threading defect concentrations
- Have shown that MgO and CaO on GaN have among the lowest reported interface defect state densities

- Will minimize issues resulting in performance limitations in GaN enhancement-mode devices.

## FY16 Goals and Milestones:

- Complete  $D_{it}$  study for MgO and CaO on GaN
  - Prepare and measure performance of lattice matched MgO-CaO alloys on GaN
  - Investigate MgO-CaO on defect-free GaN to find a maximum performance limit
  - Investigate industrial partnership for device preparation
- We gratefully acknowledge Dr. Imre Gyuk and the DOE Office of Electricity Energy Storage Program for funding this work

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<sup>1</sup>Wei, W., Nanoscale Res. Lett., 7, 2012. <sup>2</sup>Suri, R. Dissertation, NCSU, 2010. <sup>3</sup>Yang, J., J. Appl. Phys., 112, 2012.



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